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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

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APR 29 2003
GROUP 1700

IN RE APPLICATION OF:

Jean-Louis GOURET

: EXAMINER: Parker, F.J.

SERIAL NO: 10/067,418

:

FILED: FEBRUARY 7, 2002

: GROUP ART UNIT: 1762

FOR: METHOD OF MASKING, MASKING
STRIP SUITED TO THE METHOD AND
METHOD OF MANUFACTURING SAID STRIP

RESTRICTION RESPONSE

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action dated February 25, 2003, Applicant elect Group II, corresponding to claims 8-18, drawn to masking strip, classified in class 428, subclass 343 **with traverse** for prosecution in the present application.

Applicant traverses the outstanding Restriction Requirement as the outstanding Restriction Requirement has not established that an undue burden would be required if the Restriction Requirement was not issued and if all the claims were examined together. More particularly, MPEP §803 states:

If the search and examination of an entire application can be made without serious burden, the Examiner must examine it on the merits, even though it includes claims to independent or distinct inventions.

In the present application any search of the elected method claims would also include the classes and subclasses appropriate for searching the product and apparatus claims, and so then would be no undue burden if all of the claims were examined together.

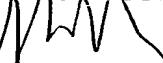
Finally, the attention of the Patent Office is directed to the change of address of Applicants' representative, effective January 6, 2003:

Oblon, Spivak, McClelland, Maier & Neustadt, P.C.
1940 Duke Street
Alexandria, VA 22314

Please direct all future correspondence to this new address.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.


Gregory J. Maier
Attorney of Record
Registration No: 25,599
Robert T. Pous
Attorney of Record
Registration No: 29,099



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(703) 413-3000
GJM:RTP:cfd